



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. ....09/212,726  
Filing Date .....December 15, 1998  
Inventor.....Klaus F. Schuegraf  
Assignee.....Micron Technology, Inc.  
Group Art Unit.....2813  
Examiner .....Blum, David S.  
Attorney's Docket No. ....MI22-1098  
Title: Semiconductor Processing Methods of Chemical Vapor Depositing SiO<sub>2</sub> on a Substrate

### RESPONSE TO DECEMBER 1, 2005 FINAL OFFICE ACTION TO ACCOMPANY RCE FILING

To: Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
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### AMENDMENTS

#### Introductory Comments

In reply to the final office action dated December 1, 2005, applicant amends and remarks as follows.